3D microwave optomechanical cavities

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Motivation

Quantum





Is quantum mechanics compatible with large, massive structures?

Nano- or micro-mechanical resonator



Cavity optomechanics



To measure mechanical motion

To create and control mechanical motion

light field



Landmarks

Teufel *et al., Nature 2011* 7.5 GHz; 10.6 MHz





Chan *et al., Nature 2011* 195 THz; 3.68 GHz



New optomechanical system: SiN membrane in 3d cavity



3D cavity and SiN membrane

22 m

AI cavity, Q>100,000





SiN membrane, Q>1,000,000



Sample preparation

Al coated membrane PECVD SiN E-beam evaporated Al sapphire substrate



Membrane window zoom-in



Coupling scheme





Cavity frequency shift: $G = \frac{\partial \omega_0}{\partial C_m} \frac{\partial C_m}{\partial x}$



Measurement setup







High Q 3d microwave cavity



Reflection coefficient of membrane-embedded cavity



Thermal motion of the membrane



Al coating: enabling electrical measurement while preserving ultrahigh Q.



Optomechanical coupling



coupling extracted with OMIT



$$C = \frac{4g_0^2}{\kappa \Gamma_m} n_d$$



driving photon numbers

Near-ground state cooling of the mm-scale membrane



Sideband cooling



Thermal occupancy $n_m = \frac{1}{e^{\hbar \omega_m / k_B T} - 1}$ For *T*=13 mK, initial occupancy $n_0 = 2200$ Occupancy with cooling $n_m = \frac{n_0}{C+1}$

$$C_{max} = 10^5 \gg 10^3$$

Measurement of cooling





Area under the curve is reduced.

De

Occupancy of the membrane



Minimum occupancy:

$$n_m = 5$$

$$T_m = 34\mu K$$

Yuan et al., Nat. Commun. 2015



High mechanical Q of SiN membranes at mK



Q factor and mechanical quantum state

- Preparation and measurement of mechanical quantum superposition state:
 - Prerequisite: deep ground state cooling
 - Cooling ability $\propto Q$
 - Longer state lifetime



Overview: silicon nitride resonators

Nanostrings: 10⁶ Cornell, JAP 2006







Trampolines: 10⁵ UCSB/Leiden, OE 2011 Sankey group, McGill; Groeblacher group, Delft: 10⁷

Lower temperature?

Membranes: 10⁷, 0.3 K Yale, APL 2007







Measurement of mechanical Q



Methods: spectral & ringdown



Optomechanical ringdown







Results



Temperature dependence

127 million: record high



Yuan et al., APL 2015

More modes



	Dev I	Dev II	
size	1.5mm x 1.5mm x 50 nm	1mm x 1mm x 50nm	
tensile stress	0.8 GPa	0.09 GPa	TUDelft Delft Tubelft Delft University o Technology

High Q vs. low Q modes



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Dev II

Conclusion

- Optomechanical system with 3d cavity and SiN membrane
- Large cooperativity that enables cooling close to ground state
- Temperature dependence of Q below 200 mK; Q exceeding 10⁸ at 14 mK
- Potentials for hybrid devices



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